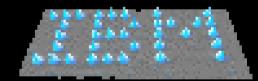


**Corporate Environmental Affairs** 

### Nanotechnology as a Tool to Advance Pollution Prevention in the Semiconductor/IT Industry

Airgap Microprocessors: Directed Self-Assembly



### Arthur Fong, PhD

US EPA Pollution Prevention through Nanotechnology Conference September 25-26, 2007 Arlington, VA

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# **Presentation Outline**

- Overview of nanotechnology in semiconductor/IT industry
- Nanotechnology Tool to enhance performance and advance pollution prevention
  - Airgap microprocessors: directed self-assembly

# Nanotechnology – Hype vs. Substance - 1



- \$1 Trillion business by 2011-2015 (NSF, 2001)
- \$2.6 Trillion of manufactured goods by 2014 (Lux Research, 2006)



# Nanotechnology – Hype vs. Substance - 2

#### "Nano"? products everywhere





Pentel - Nanocapsule-imbued scented pencil lead

Aromatherapy + nanotechnology

# "Magic Nano" glass and ceramic tile sealant aerosol spray

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# Nanotechnology – Hype vs. Substance - 3

#### Applied use currently limited, but ramping up fast

- Project on Emerging Nanotechnologies,
   Nanotechnology Consumer Products Inventory
- Nanoelectronics leads nanotechnology commercialization

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# Nanoelectronics Market Data and Forecast

- 2005 Worldwide market ~ US \$60 billion
- 2010 Worldwide projection ~ US \$250 billion

### Nanoelectronics

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- Displays e.g., field emission display
- MEMS/NEMS e.g., nano-mechanical data storage
- Optoelectronics/sensors e.g., photonic devices
- Semiconductors e.g., transistors and interconnects
- Hard-disk storage e.g., magnetic storage

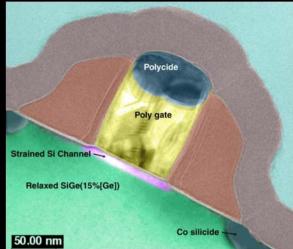


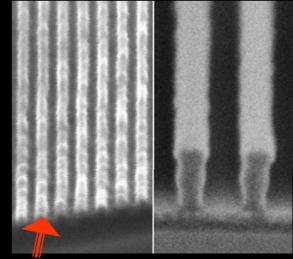
# Nanotechnology is Not New in Semiconductor/IT Industry

- Early stages
  - 100 nm Bipolar transistor base (ca. 1970)
  - 100 nm CMOS (complementary metal oxide semiconductor) gate oxide (ca. 1970)

#### More recently

- Transistor physical gate length ~ 70 nm (2000)
- 90-nm Technology node gate oxide of
  1.2 nm, about 4 atomic-layers thick
  (2003)
- Electron beam lithography 40-70 nm





29.9 nm, Deep-UV optical lithography

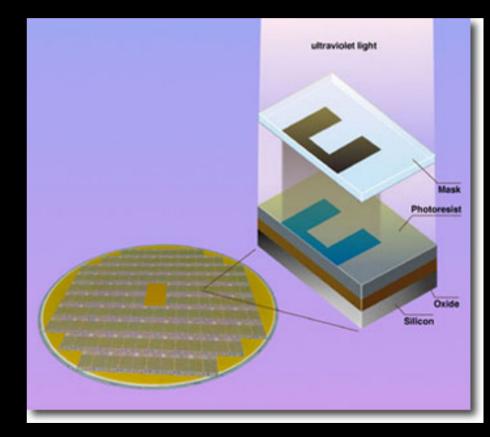
## Current Semiconductor/IT Nanotechnology - Photolithography

- Masking
- Etching

8

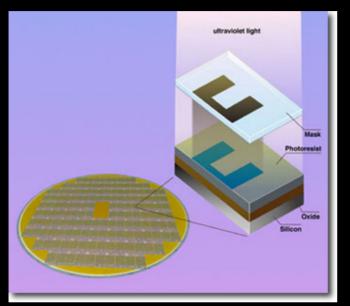
#### Examples of chemicals in photolithography

- Photoresist (photoactive organic polymers)
- Developers (tetramethyl ammonium hydroxide)
- Solvents and cleaning agents
- Etching (acids, chlorine)
- Stripping (acids, alkalines)



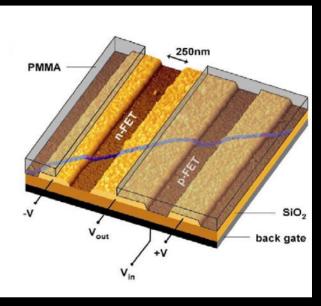


# Traditional Semiconductor/IT Nanotechnology and Engineered Nanomaterials



#### Semiconductor/IT nanotechnology

- Minimum feature size of devices at nanoscale for decades
- Photolithography
- "Does not present any unique hazards" (Royal Society & Royal Academy of Engineering, 2004)



- Engineered nanomaterials
  - Discrete manufactured nanoparticles, nanotubes, and other nanomaterials
- Nanomaterials fixed within products



# Nanotechnology – A Critical Key to Future Development of Semiconductor/IT Industry

(International Technology Roadmap for Semiconductors, 2005, 2006)

#### Potential solutions to technical challenges

 Approaching limits of current manufacturing processes and materials

#### Potential solutions to business challenges

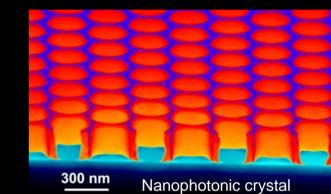
- Escalating fab costs
- Opportunity for diversification
- Tremendous opportunity for environmental, health, and safety benefits – pollution prevention
  - Energy/resource conservation manufacturing/processes
  - Waste minimization, e.g., self-assembly
  - Energy efficient products

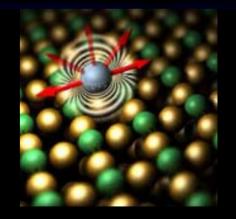


Examples of IBM Nanotechnology R&D Performance Enhancement and Pollution Prevention

- By 2010, the codified information base of the world is expected to double every 11 hours
- Nanophotonics Control over light signal
  - Optical Networks
- Atomic magnetism single-atom data storage (08/2007)
- Single-molecule switching molecular computers comprising of just a few molecules (08/2007)
- Airgap microprocessors (05/2007)
  - Directed self-assembly

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Magnetic orientation of an iron atom



<u>Self-Assembly</u>: How Will We Manufacture at the Nanoscale?

Two visions of nanofabrication:

- "Old"
- Top down
- Lithography
- Digital
- Depend on low error rates
- Molecular assemblers

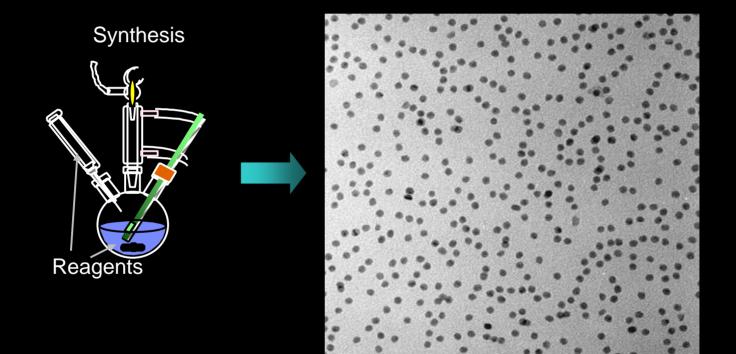
- "New"
- Bottom up
- Chemical synthesis
- Analog
- Tolerate high error rates
- Self-assembly

# This is a false dichotomy!

T. Theis, IBM Research



# Allowing a Few Components to Approach Equilibrium Will Produce Only Simple Structures



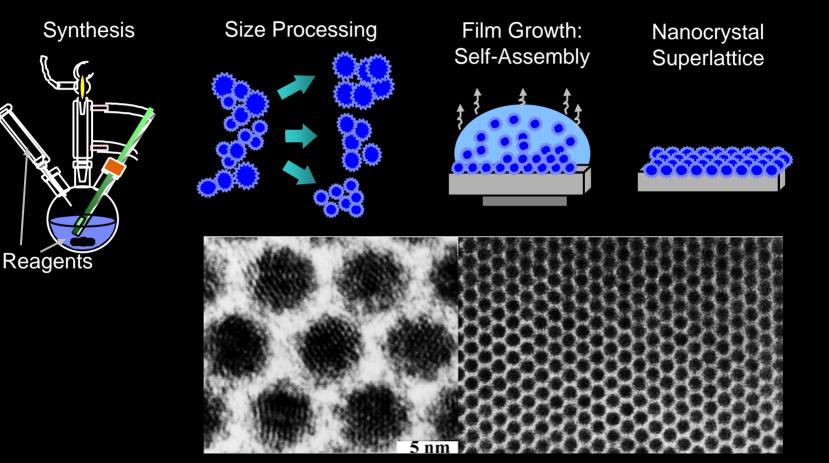
#### T. Theis, IBM Research

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# "Guiding" or "Directing" the Equilibration Process:

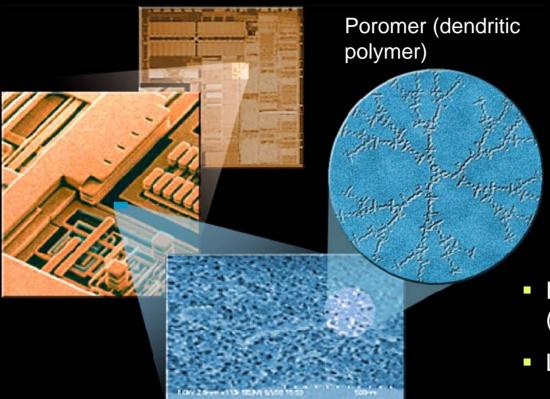
## Semiconductor Nanocrystals



#### T. Theis, IBM Research



# Goal: Incorporate Nanoscale Components in IT Systems



Porous dielectric for on-chip wiring

# 

- IBM World's first single-molecule (carbon nanotube) computer circuit
- Leading to new class of computers
  - Smaller
  - Faster
  - Consume less power

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T. Theis, IBM Research



Directed Self-Assembly Nanotechnology to Create Airgap Microprocessors (05/2007)

- Current process nanoscale wires in microprocessors insulated with glass-like material
- Airgap vacuum gaps to insulate nanoscale wires
- Significant enhancement of performance
  - Equivalent of two generations of Moore's Law improvement



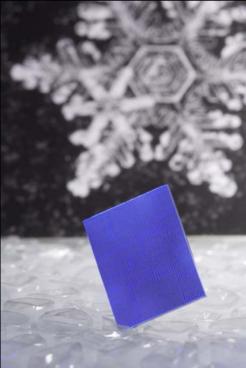
#### **IBM Fellow Dan Edelstein**

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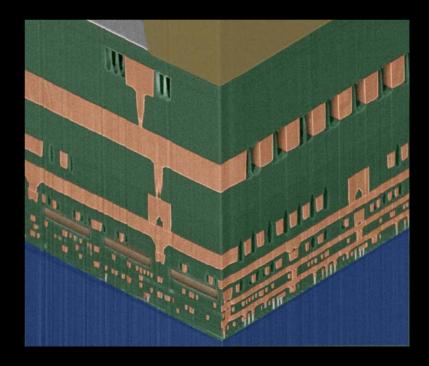


# Airgap: Directed Self-Assembly

- Nature's ability to form intricate patterns (snowflakes, sea shells)
  - Mix of compounds/polymers
  - Pour onto silicon wafer
  - Bake directed self-assembly
  - Trillions of uniform 20-nm holes (vacuum "airgaps") in wafer



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# Airgap: Directed Self-Assembly Animation



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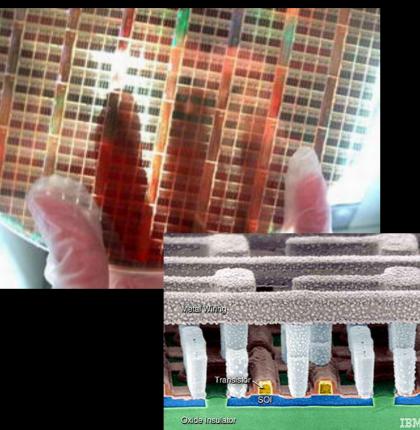
### Breakthrough of Directed Self-Assembly Airgap Nanotechnology

- Current process lithography
  - Masking
  - Etching
- Examples of chemicals in photolithography
  - Photoresist (photoactive organic polymers)
  - Developers (tetramethyl ammonium hydroxide)
  - Solvents and cleaning agents
  - Etching (acids, chlorine)
  - Stripping (acids, alkalines)

- Self-assembly 20-nm vacuum holes
  - 5x smaller than lithography
  - Not possible with lithography
- Manufacturing
  - Resource and energy conservation
  - Waste minimization
- Product
  - 35% Faster
  - 15% Less energy consumption



#### Why Would Even Small Gains in Energy Efficiency Result in Major Advances in Pollution Prevention?



Silicon Wafer



#### Last year the world produced more transistors (and at a lower cost) than grains of rice

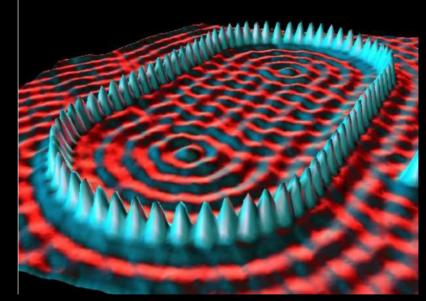
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# Thank you

#### Contact information

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Using the scanning tunneling microscope (STM), electron formations can be viewed. Above, electrons are surrounded by 48 iron atoms, individually positioned with the same STM used to image them - IBM Almaden Research Center.